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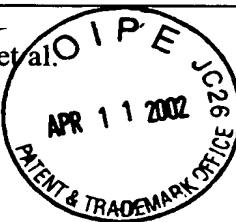
**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of: Shrinivasan et al.

Application No.: 10/067,520

Filed: February 5, 2002

Title: APPARATUS AND METHODS FOR  
PROCESSING SEMICONDUCTOR  
SUBSTRATES USING SUPERCRITICAL  
FLUIDS



Attorney Docket No.:  
NOVLP029/NVLS-000495

Examiner: Kornakay  
Not yet assigned

Group: 2811 F746

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Commissioner for Patents  
Washington, DC 20231

Dear Sir:

The references listed in the attached PTO Form 1449, copies of which are attached, may be material to examination of the above-identified patent application. Applicants submit these references in compliance with their duty of disclosure pursuant to 37 CFR §§1.56 and 1.97. The Examiner is requested to make these references of official record in this application.

This Information Disclosure Statement is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that these references indeed constitute prior art.

This Information Disclosure Statement is: (i) filed within three (3) months of the filing date of the above-referenced application, (ii) believed to be filed before the mailing date of a first Office Action on the merits, or (iii) believed to be filed before the mailing of a first Office Action after the filing of a Request for Continued Examination under §1.114. Accordingly, it is believed that no fees are due in connection with the filing of this Information Disclosure

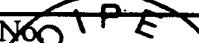
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Statement. However, if it is determined that any fees are due, the Commissioner is hereby authorized to charge such fees to Deposit Account 500388 (Order No. NVLSP029).

Respectfully submitted,  
BEYER WEAVER & THOMAS, LLP

  
Brian D. Griedel  
Registration No. 48,425

P.O. Box 778  
Berkeley, CA 94704-0778

<b>Form 1449 (Modified)</b> <b>Information Disclosure</b> <b>Statement By Applicant</b>  <b>(Use Several Sheets if Necessary)</b>	Atty Docket No. <b>NOVLP029</b> Application No.: <b>10/067,520</b> Applicant: <b>Shrinivasan et al.</b> Filing Date <b>February 5, 2002</b>  <b>Group 2811</b>
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## U.S. Patent Documents

### **Foreign Patent or Published Foreign Patent Application**

## Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	A	Costantini et al., "Supercritical Fluid Delivery and Recovery System for Semiconductor Wafer Processing", Pub. No.: US 2001/0050096 A1, Pub. Date: Dec. 13, 2001, Appl. No.: 09/837,507, Filed: April 18, 2001, pages 1-15
	B	Chandra et al., "Supercritical Fluid Cleaning Process for Precision Surfaces", Pub. No.: US 2002/0014257 A1, Pub Date: Feb. 7, 2002, Appl. No. 09/861,298, Filed: May 18, 2001, pages 1-21.
Examiner		Date Considered

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.